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THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re patent application of

Art Unit 1763

Seung-un KIM, et al.

Examiner: S. Macarthur

Serial No. 10/800,735

Confirmation No. 1171

Filed: March 16, 2004

For: APPARATUS AND METHOD FOR SUPPLYING CHEMICALS
IN CHEMICAL MECHANICAL POLISHING SYSTEMS

AMENDMENT UNDER 37 C.F.R. §1.111

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, Va. 22313-1450

Sir:

INTRODUCTORY COMMENTS

In response to the Office action mailed September 8, 2004, the following amendments and remarks are respectfully submitted in connection with the above-identified application:

Amendments to the Claims are reflected in a listing of claims, which begins on page 2 of this paper.

Remarks begin on page 5 of this paper.